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BRIEF DESCRIPTION OF THE DRAWINGS

- [00011] FIG. 1 depicts a multiple charged particle beam apparatus.
- [00012] FIGS. 2A, 2B depict electromagnetic fields for multiple beam arrangements.
- [00013] FIGS. 3A, 3B, 3C, 3D depict individual beam paths.
- [00014] FIG. 4 depicts a plot of an undesired deflection field for peripheral beams in a beam array.
- [00015] FIGS. 5A, 5B, ^{5C}~~5C~~ depict detail of the electron gun of FIG. 1. *JB, 5/10/07*
- [00016] FIGS. 6A, 6B, 6C depict detail of the beam aperture and valve of FIG. 1.
- [00017] FIG. 7 depicts one of the columns of FIG. 1.
- [00018] FIG. 8 depicts an electrical isolation arrangement for the detectors.
- [00019] FIG. 9 depicts a focussing and adjusting process for the FIG. 1 apparatus.
- [00020] FIG. 10A, 10B illustrate stage travel for the FIG. 1 apparatus.